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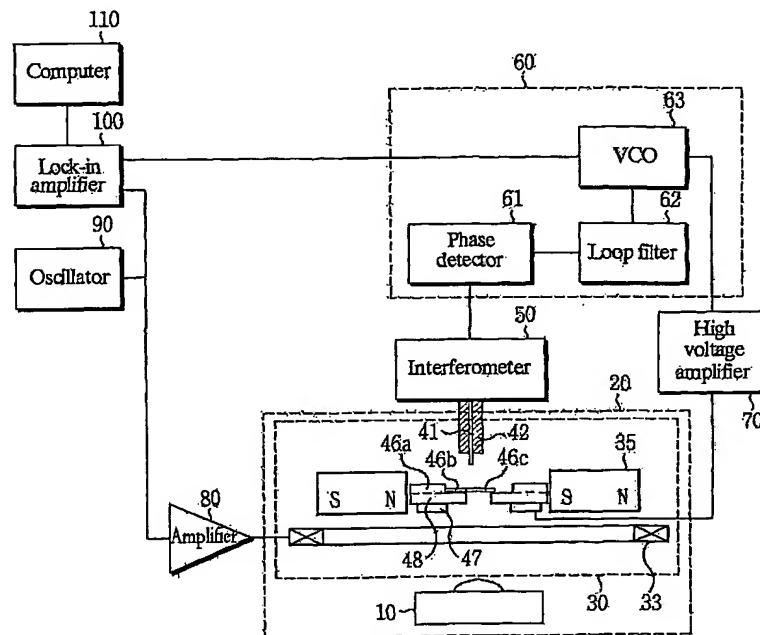
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(54) Title: ULTRA SENSITIVE IN-SITU MAGNETOMETER SYSTEM



(57) Abstract: The present invention relates to an ultra sensitive in-situ magnetometer system, and more particularly to an ultra sensitive in-situ magnetometer system that can in-situ monitor a magnetic moment of a magnetic thin film with sub-monolayer precision while depositing and growing the magnetic thin film in an ultra high vacuum (UHV) chamber.



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